

Correction

Correction: Liu, W. *et al.* A Highly Sensitive Humidity Sensor Based on Ultrahigh-Frequency Microelectromechanical Resonator Coated with Nano-Assembled Polyelectrolyte Thin Films. *Micromachines*, 2017, 8, 116

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In the published paper [1], there is an error in Figure 3. The red curve in Figure 3b was deleted by mistake during the revisions. The correct figure should read as follows:

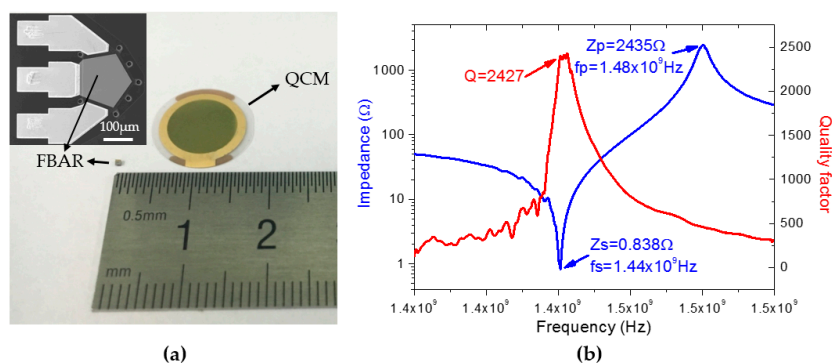


Figure 3. FBAR characterization. (a) A comparison of the size between FBAR and quartz crystal microbalance (QCM). The top-left inset shows the top-view scanning electron microscopy (SEM) image of FBAR; (b) magnitude of impedance and Q value over frequency.

The authors apologize for any inconvenience caused by the error. The manuscript will be updated online and the previous version will remain available on the article webpage.

Reference

1. Liu, W.; Qu, H.; Hu, J.; Pang, W.; Zhang, H.; Duan, X. A Highly Sensitive Humidity Sensor Based on Ultrahigh-Frequency Microelectromechanical Resonator Coated with Nano-Assembled Polyelectrolyte Thin Films. *Micromachines* **2017**, *8*, 116. [CrossRef]



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